

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1765
Examiner Ahmed, Shamim
Attorney's Docket No.MI22-1106
Title: Plasma Etching Process

RESPONSE TO APRIL 5, 2006 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENTS

Introductory Comments

In response to the Office Action dated April 5, 2006, applicant amends and remarks as follows.